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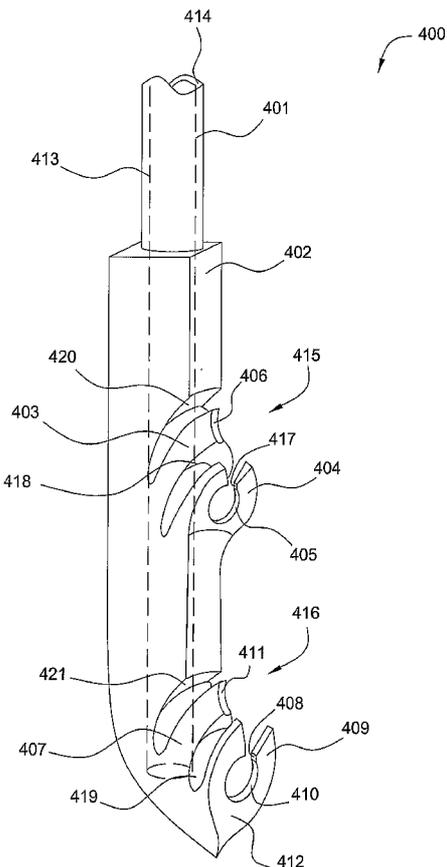
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[Continued on next page]

(54) Title: METHOD OF MINIMAL WAFER SUPPORT ON BEVEL EDGE OF WAFER



(57) Abstract: The present invention generally provides a method and apparatus for supporting and transferring a substrate in and out a wet cleaning chamber with minimal contact. One embodiment of the present invention provides an apparatus for support and transferring a substrate. The apparatus comprises a frame connected with an actuator configured to move the frame, two posts extending from the frame, two end effector bodies, each of the two end effector bodies formed on a respective one of the two posts, wherein the frame and the end effector bodies are positioned on opposite ends of the two posts, and two contact assemblies extending from each of the two end effector bodies, wherein the two contact assemblies are configured to receive and support the substrate near a bevel edge.

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**A. CLASSIFICATION OF SUBJECT MATTER**  
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 USPC: 438/243  
 According to International Patent Classification (IPC) or to both national classification and IPC

**B. FIELDS SEARCHED**  
 Minimum documentation searched (classification system followed by classification symbols)  
 USPC: 438/243

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched  
 USPC: 348/689

Electronic data base consulted during the international search (name of data base and, where practicable, search terms used)  
 PubWEST(USPT,PGPB,EPAB,JPAB); DialogPRO; WIPO, EPO, CITESEER, Google patents, Google Scholar. Search Terms Used:  
 semiconductor substrate end effector end effector (inclined or bevel or incline or tilt) support transfer radial lateral tungsten carbide  
 polymer chemical resistive coating actuator

**C. DOCUMENTS CONSIDERED TO BE RELEVANT**

Category*	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	US 6,726,848 B2 (Hansen et al.) 27 April 2004 (27.04.2004) entire document especially col 15, ln 64 - col 16, ln 64 and Figs. 7A to 7E	1 - 20

Further documents are listed in the continuation of Box C.

\* Special categories of cited documents:

"A" document defining the general state of the art which is not considered to be of particular relevance	"T" later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention
"E" earlier application or patent but published on or after the international filing date	"X" document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone
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"O" document referring to an oral disclosure, use, exhibition or other means	"&" document member of the same patent family
"P" document published prior to the international filing date but later than the priority date claimed	

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